



ITW

PATENT

Attorney Docket No.
033082 M 274

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the application of:)	CONFIRMATION NO.: 3704
)	
Kazuhide HASEBE, et al.)	
)	
U.S. Serial No.: 10/549,851)	Group Art Unit: 2812
)	
Filed: September 23, 2005)	Examiner: Reema Patel

For: METHOD FOR CLEANING FILM-FORMING UNIT

RESPONSE TO RESTRICTION REQUIREMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir :

A response to the Office Action mailed May 14, 2007 is due by June 14, 2007. The Action required restriction among the following:

- Group I of claims 1, 4, 6-11, 12, 15, and 16-20,
- Group II of claims 2, 6-11, 13, and 16-20, and
- Group III of claims 3, 6-11, 14, and 16-20.

Applicants hereby elect Group I of claims 1, 4, 6-11, 12, 15, and 16-20, drawn to a cleaning method and apparatus which involve a nitrogen-including gas being activated to nitride the surface of a reaction chamber, for examination in this application.

Applicants reserve the right to file divisional application(s) for the non-elected claims in due course.

It is submitted that this application now is in condition for examination on the merits and early action in that regard is solicited.

Respectfully submitted,
SMITH, GAMBRELL & RUSSELL, LLP



Michael A. Makuch – Registration No. 32,263
1850 M Street, NW – Suite 800
Washington, DC 20036
Tel : 202 263 4300
Fax : 202 263 4329

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